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Brendy Belony
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Attorney Docket No.: NECF 17.638B

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: Mami MIYASAKA

Serial No.:

Filed:

Title: **ELECTRON BEAM EXPOSURE MASK, ELECTRON BEAM
EXPOSURE METHOD, METHOD OF FABRICATING
SEMICONDUCTOR, AND ELECTRON BEAM EXPOSURE
APPARATUS**

Examiner:

Group Art Unit:

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

SIR :

Prior to examination on the merits and prior to calculation of the filing fee, please
amend the above-captioned application as follows: